

2025 NANO-FAB Center training schedule

▲ Safety training & test

Date	Description	
	Safety training	Safety training test
Monthly	1 ST Monday(10:00~12:00)	1 ST Friday(14:00~15:00)

▲ Process equipment training

Date/Time		Description					
		MON	TUE		THU	FRI	
Week #1	10:00~11:00	Photo lithography (Mask aligner)	E-Beam evaporator#2	Sputter (DC, RF, HSC)	E-beam lithography(attached)	Dry etching (ICP, RIE)	Wet station
	11:00~11:30						
	13:00~14:00		PE-CVD				
	14:00~15:00		LP-CVD		Maskless Laser lithography		
	15:00~16:00		Thermal ALD			Surface profiler	
	16:00~17:00		Dicing saw	Furnace		PR strip	
	17:00~18:00		Ellipsometer				
Week #2	10:00~11:00	Photo lithography (Mask aligner)	E-Beam evaporator#2	Sputter (DC, RF, HSC)	E-beam lithography(attached)	Dry etching (ICP, RIE)	Wet station
	11:00~11:30						
	13:00~14:00		PE-CVD				
	14:00~15:00		LP-CVD		Maskless Laser lithography		
	15:00~16:00		Thermal ALD			Surface profiler	
	16:00~17:00		Dicing saw	Furnace		PR strip	
	17:00~18:00		Ellipsometer				
Week #3	10:00~11:00	Photo lithography (Mask aligner)	E-Beam evaporator#2	Sputter (DC, RF, HSC)	E-beam lithography(attached)	Dry etching (ICP, RIE)	Wet station
	11:00~11:30						
	13:00~14:00		PE-CVD				
	14:00~15:00		LP-CVD		Maskless Laser lithography		
	15:00~16:00		Thermal ALD			Surface profiler	
	16:00~17:00		Dicing saw	Furnace		PR strip	
	17:00~18:00		Ellipsometer				
Week #4	10:00~11:00	Photo lithography (Mask aligner)	E-Beam evaporator#2	Sputter (DC, RF, HSC)	E-beam lithography(attached)	Dry etching (ICP, RIE)	Wet station
	11:00~11:30						
	13:00~14:00		PE-CVD				
	14:00~15:00		LP-CVD		Maskless Laser lithography		
	15:00~16:00		Thermal ALD			Surface profiler	
	16:00~17:00		Dicing saw	Furnace		PR strip	
	17:00~18:00		Ellipsometer				

- ※ Applicant should check the training schedule and apply for training in each category.
- ※ Please complete the safety training first, then apply for the equipment training..
- ※ Each training session requires a minimum of 3 participants. If the number of applicants is too low, the schedule may be changed.
- ※ Training for equipment not mentioned above require a separate e-mail application/request.
- ※ After 5 minutes of starting participant, will not be allowed into the training session.
- ※ Absence without permission will result in exclusion from registration for the next 1 months of all training sessions.
- ※ 교육일정을 확인하여 각 분야별 교육을 신청하시기 바랍니다.
- ※ 안전교육을 이수한 이후, 장비교육 신청 해 주세요.
- ※ 각 교육별 신청자는 3명이며, 신청수가 저조할 경우 그 회차의 교육 일정이 변경 될 수 있습니다.
- ※ 명단에 없는 장비의 교육은 각 장비 담당자에게 이메일로 신청하시기 바랍니다.
- ※ 교육 시작 시간 5분 뒤에는 교육에 참석 할 수 없습니다.
- ※ 교육 신청 후 무단으로 불참시, 이후 1개월간 클린룸에서 진행되는 교육에 참석 할 수 없습니다.